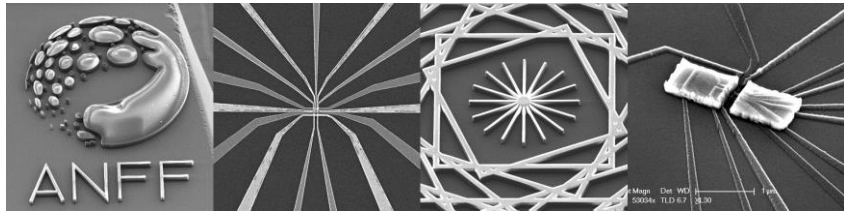




THE UNIVERSITY OF  
**SYDNEY**  
—  
**Research and  
Prototype  
Foundry**



## **The First Australian Direct Write Lithography Workshop 4-6 December 2019**

The Research & Prototype Foundry at the University of Sydney invites you to attend a FREE one-day workshop that focuses on direct write lithography technologies, including electron, photon, and ion beam lithography. This workshop is the first of its kind in Australia and is a joint collaboration between ANFF and Microscopy Australia.

The program features technical experts and equipment manufacturers to introduce a broad spectrum of state-of-the-art lithography capabilities and case studies. The event also offers plenty of opportunities for participants to share and exchange fabrication knowledge in dedicated parallel group sessions.

Immediately following the workshop, participants can choose to stay on for either a two-day training course on GenISys Beamer, a software package that targets electron beam lithography users, or a half-day practical introduction to direct write photolithography in our world-class cleanroom.

**Program details, including travel funding, will be released closer to the date of the workshop**

### **Organisers**

#### **ANFF**

Jason Hwang, Research & Prototype Foundry  
University of Sydney  
[jason.hwang@sydney.edu.au](mailto:jason.hwang@sydney.edu.au)

#### **Microscopy Australia**

Elliot Cheng, Centre for Microscopy & Microanalysis  
University of Queensland  
[h.cheng6@uq.edu.au](mailto:h.cheng6@uq.edu.au)

## Where

Seminar Room LG17  
Physics Road Learning  
Hub  
University of Sydney

## When

**Direct Write Lithography Workshop**  
9am to 5pm, 4 December

**Beamer Training**  
9am to 5pm, 5 & 6 December

**Direct Write Photolithography Practical**  
9am to 1pm, 5 December

***Catering will be provided***

Please RSVP to the event(s) you wish to attend using the QR code provided

Note that the Beamer Training and Photolithography Practical are run concurrently

**Limited Seats Available - RSVP now**



# The First Australian Direct Write Lithography Workshop 4-6 December 2019

## Schedule

	Day 1 DWL Workshop	Day 2		Day 3
9am	Please refer to DWL Workshop Program	Genlsys Beamer/Tracer training PART 1	Photolithography Practical  Morning groups	Genlsys Beamer/Tracer training PART 3
		Lunch		Lunch
5pm		Genlsys Beamer/Tracer training PART 2	Photolithography Practical  Afternoon groups	Genlsys Beamer/Tracer training Advanced

### Day 1 DWL Workshop Program

<b>9:00</b>	<i>Welcome and Introductions</i>
<b>9:10</b>	Elionix
<b>9:40</b>	Comparison of various EBL resists – Gayatri Vaidya and Fouad Karouta, ANU
<b>10:00</b>	Raith
<b>10:30</b>	<i>Morning Tea</i>
<b>11:00</b>	Helium-ion beam – Anders Barlow, UM
<b>11:20</b>	Nanoscribe
<b>11:50</b>	Two-photon polymerization – Nick Lee, UQ
<b>12:10</b>	<i>Lunch</i>
<b>13:20</b>	Heidelberg
<b>13:50</b>	NanoFrazor – Hemayet Uddin, MCN
<b>14:10</b>	Facility overview - UTS
<b>14:30</b>	Genlsys Beamer
<b>15:00</b>	<i>Casual discussion sessions + Afternoon tea</i>